## **AMENDMENTS TO THE CLAIMS**

Please amend the claims as follows:

Claim 1 (Currently Amended): A microwave tunable device <u>for use in</u> one of a phase array antenna system and a satellite communication system, comprising:

a MgO substrate; and

a ferroelectric/dielectric ( $Ba_{1-x}$ , $Sr_x$ ) $TiO_3$  (BST) thin film of a (111) direction which is formed on the MgO substrate, wherein x is a number between 0 and 1 and represents a composition ratio; and

an electrode pattern formed on the ferroelectric/dielectric BST thin film.

Claim 2 (Original) The microwave tunable device as recited in claim 1, wherein the ferroelectric/dielectric BST thin film is grown by performing a laser ablation.

Claim 3 (Canceled)

Claim 4 (New) A method for fabricating a microwave tunable device for use in one of a phase array antenna system and a satellite communication system, comprising the steps of:

forming a substrate;

forming a ferroelectric/dielectric ( $Ba_{1-x}$ , $Sr_x$ ) $TiO_3$  (BST) thin film by performing a laser ablation; and

forming an electrode pattern on the ferroelectric/dielectric BST thin film by performing photolithography and etching processes.

Claim 5 (New) The method as recited in claim 4, wherein the substrate is MgO.

Claim 6 (New) The method as recited in claim 4, wherein an orientation of the ferroelectric/dielectric BST thin film is a (111) direction on the substrate.

Claim 7 (New) The method as recited in claim 6, wherein the ferroelectric/dielectric BST thin film is deposited under about 825°C.